

# Guojin Chen

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RESEARCH INTERESTS	I am interested in Machine Learning, EDA, VLSI design. My current focuses include: <ul style="list-style-type: none"><li>• Machine Learning in VLSI Design.</li><li>• Reinforcement learning, computer vision.</li></ul>	
EDUCATION	<b>The Chinese University of Hong Kong</b> <b>M.Sc. in Computer Science</b> <ul style="list-style-type: none"><li>• Advisor: Prof. Bei Yu</li></ul>	Hong Kong Sep 2019 – Nov 2020
	<b>Huazhong University of Science and Technology</b> <b>Bachelor of Computer Science</b>	Wuhan, China Sep 2015 – Jun 2019
RELEVANT WORKING EXPERIENCE	<b>Smartmore Co.Ltd.</b> <b>Research Intern</b>	SHENZHEN, China Nov 2020 – Jan 2021
	<b>Tencent Technology Co.Ltd.</b> <b>Research Intern</b>	SHENZHEN, China May 2018 – Nov 2018
AWARDS	<b>Scholarship</b> <ul style="list-style-type: none"><li>• Distinguished Academic Performance Scholarship, CUHK.</li><li>• National Encouragement Scholarship, HUST, Ministry of Education, PRC</li><li>• First Class Scholarship, HUST, the highest scholarship in HUST.</li></ul>	May 2020 Nov 2016 2018, 2019
	<b>Internship</b> <ul style="list-style-type: none"><li>• First Prize, Tencent SNG Hack Week.</li><li>• Excellent Intern, Tencent.</li></ul>	Jun 2019 Sep 2019
PROJECTS	<b>DAMO</b> : Towards High Accuracy DL-Based OPC With Deep Lithography Simulator. This paper present a novel method for Deep Learning based OPC which results surpass the famous OPC tool Mentor Calibre. The manuscript was accepted by ICCAD2020. <b>CUDA-OPC</b> : This is a CUDA acceleration project that aims to improve the ILT computation efficiency, it speeds up the lithography process nearly 40 times than before.	
SKILLS	<b>Programming</b> C/C++, Python, Ruby, Matlab, $\text{\LaTeX}$ , Bash, Javascript, Rust, Java <b>Machine Learning</b> Skilled in Pytorch, Tensorflow, and CUDA programming. <b>Tools</b> Vim, Git, macOS, Linux	
TALKS	1. CUDA based Convolution and FFT on OPC. <i>CUDA Group Presentation.</i> , CUHK. Mar 2020 2. DLS-DMO: High Accuracy DL-Based OPC With DLS. <i>CUDA Group Presentation.</i> , CUHK. May 2020	

## PUBLICATIONS

- [1] W. Li, **G. Chen**, H. Yang, R. Chen, and B. Yu, “Learning point clouds in eda. (**Invited Paper**),” in *ACM International Symposium on Physical Design, (ISPD '21)*, Mar. 2021.
- [2] Z. Yu, **G. Chen**, Y. Ma, and B. Yu, “A gpu-enabled level set method for mask optimization,” in *IEEE/ACM Proceedings Design, Automation and Test in Europe, (DATE '21)*, Nov. 2020.
- [3] **G. Chen**, W. Chen, Y. Ma, H. Yang, and B. Yu, “DAMO: Deep agile mask optimization for full chip scale,” in *Proceedings of the 39th International Conference on Computer-Aided Design, (ICCAD '20)*, Nov. 2020, pp. 1–9.